



Addendum

Invention Title:

METHOD OF APPLYING THE ANALYSIS OF SCRUB MARK MORPHOLOGY AND LOCATION TO THE EVALUATION AND CORRECTION OF SEMICONDUCTOR TESTING, ANALYSIS AND MANUFACTURE.

Attorney Docket: 044182-0308512

Client Reference:



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of: STROM
Application No.: 10/788,670

Confirmation Number: 3585
Group Art Unit: 2829

Filed: February 27, 2004

Examiner:

Title: METHOD OF APPLYING THE ANALYSIS OF SCRUB MARK MORPHOLOGY AND LOCATION TO THE EVALUATION AND CORRECTION OF SEMICONDUCTOR TESTING, ANALYSIS AND MANUFACTURE.

REPLY UNDER 37 C.F.R. § 1.111(b)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action dated October 5, 2004, the time for reply having been extended by concurrent petition and payment of fee, Applicant submits the following Remarks.

The pending claims are reflected in the **Listing Of Claims** that begins on page 2 of this paper.

Remarks begin on page 3 of this paper.